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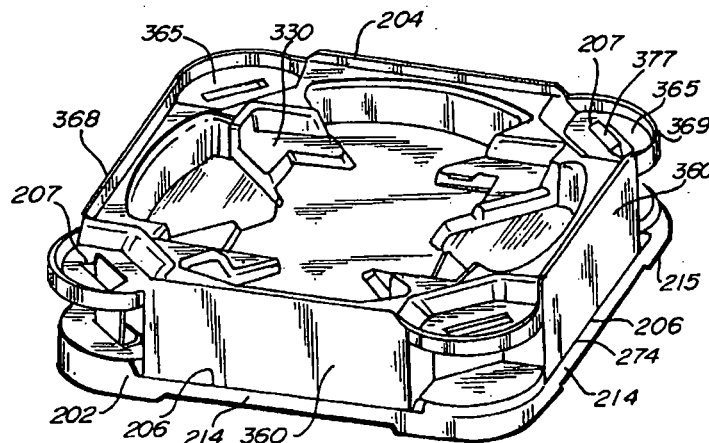
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(54) Title: SHOCK RESISTANT VARIABLE LOAD TOLERANT WAFER SHIPPER



(57) Abstract: A wafer shipper (202, 204) for stacked wafers (510) provides significantly improved resistance to shock and impact as well as flexibility and tolerance in wafer capacities and guidance in optimal amount of packing material. These characteristics are provided by unique structural configurations that provide rigidity and desirable distribution of impact forces. The shipper (202, 204) has a base (202) and a top cover (204) both of which have a nominal wall that primarily forms all of the features of the respective components. The base (202) has four sides (214), four corners, and arcuate wall segments (208) defining a wafer stack pocket. The sides are formed of a downwardly extending nominal wall portion (216, 218, 200) and an upwardly extending lip (274). Both adjoin a nominal wall defining a planar surface (210) that extends around the base (202) and forms a seat for the top cover (204). A feature and advantage of particular embodiments of the invention is the unique form fit whereby impact forces that are received on the corners and/or sides of the top cover (204) are transferred to the base (202) through the top cover (204) to upright portions on the opposite side of the base (202) from where the impact occur.



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